



ASMP.055DV1

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoh et al.
Appl. No. : 10/759,953
Filed : January 16, 2004
For : SEMICONDUCTOR-
PROCESSING DEVICE
PROVIDED WITH A REMOTE
PLASMA SOURCE FOR SELF-
CLEANING

Examiner : Alejandro Mulero, Luz. L.
Group Art Unit : 1763

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

January 12, 2007

(Date)

Eli A. Loots, Reg. No. 54,715

RESPONSE TO FINAL OFFICE ACTION

Mail Stop AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed on November 16, 2006, Applicants request consideration of the following remarks:

Statement of the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.